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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/092,115	06/05/1998	MAUREEN A. HANRATTY	TI-25277	5690

23494 7590 05/03/2005

TEXAS INSTRUMENTS INCORPORATED  
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EXAMINER

NGUYEN, KHIEM D

ART UNIT PAPER NUMBER

2823

DATE MAILED: 05/03/2005

Please find below and/or attached an Office communication concerning this application or proceeding.



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09/092115

APPLICATION NO./ CONTROL NO.	FILING DATE	FIRST NAMED INVENTOR / PATENT IN REEXAMINATION	ATTORNEY DOCKET NO.
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EXAMINER
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ART UNIT	PAPER
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052005

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Please find below and/or attached an Office communication concerning this application or proceeding.

Commissioner for Patents

Please see attached examiner's amendment

Art Unit: 2823

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

The Abstract is apparently missing from the application file.

Therefore, the following abstract has been inserted by examiner's amendment:

**--ABSTRACT**

The present invention provides integrated circuit fabrication with a silicon oxynitride antireflective layer for gate location plus patterned photoresist linewidth reduction for gate length definition followed by interconnect definition without patterned photoresist linewidth reduction. This has the advantages of an antireflective layer compatible with linewidth reduction and polysilicon etching. --

**Conclusion**

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Khiem D Nguyen whose telephone number is (571) 272-1865. The examiner can normally be reached on Monday-Friday (8:00 AM - 5:00 PM).

If attempts to reach the examiner by telephone are unsuccessful, the

Primary examiner, W. David Coleman, can be reached on (571) 272-1856. The fax phone number for the organization where this application is

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assigned is 703-872-9306.



OLIK CHAUDHURI  
SUPERVISORY PATENT EXAMINER  
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